Inventors' Name Search

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Search Results - Record(s) 1 through 4 of 4 returned.

1. Document ID: US 20050048778 A1

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L7: Entry 1 of 4

File: PGPB

Mar 3, 2005

PGPUB-DOCUMENT-NUMBER: 20050048778

PGPUB-FILING-TYPE: new

DOCUMENT-IDENTIFIER: US 20050048778 A1

TITLE: Use of thin SOI to inhibit relaxation of SiGe layers

PUBLICATION-DATE: March 3, 2005

INVENTOR-INFORMATION:

NAME CITY STATE COUNTRY RULE-47 Bedell, Stephen W. Wappingers Falls NY US Chen, Huajie Wappingers Falls NY US Mohegan Lake Fogel, Keith E. NY US Sadana, Devendra K. Pleasantville US NY

US-CL-CURRENT: 438/689; 117/4

| Full | Title | Citation | Front | Review | Classification | Date | Reference | Sequences | Attachments | Claims | KUMC Drawn De |
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2. Document ID: US 20050003229 A1

L7: Entry 2 of 4

File: PGPB

Jan 6, 2005

PGPUB-DOCUMENT-NUMBER: 20050003229

PGPUB-FILING-TYPE: new

DOCUMENT-IDENTIFIER: US 20050003229 A1

TITLE: Defect reduction by oxidation of silicon

PUBLICATION-DATE: January 6, 2005

INVENTOR-INFORMATION:

NAME CITY STATE COUNTRY RULE-47 Bedell, Stephen W. Wappingers Falls NY US Chen, Huajie Wappingers Falls US NY Domenicucci, Anthony G. New Paltz NY US Fogel, Keith E. Mohegan Lake NY US

Record List Display Page 2 of 3

Sadana, Devendra K.

Pleasantville

NY US

US-CL-CURRENT: 428/641; 438/514

Full Title Citation Front Review Classification Date Reference Sequences Attachments Claims 10MC Draw De

3. Document ID: US 20040259334 A1

L7: Entry 3 of 4

File: PGPB

Dec 23, 2004

PGPUB-DOCUMENT-NUMBER: 20040259334

PGPUB-FILING-TYPE: new

DOCUMENT-IDENTIFIER: US 20040259334 A1

TITLE: High-quality SGOI by annealing near the alloy melting point

PUBLICATION-DATE: December 23, 2004

INVENTOR-INFORMATION:

NAME CITY STATE COUNTRY RULE-47 Bedell, Stephen W. NY Wappingers Falls US Chen, Huajie New Paltz NY US Domenicucci, Anthony G. Mohegan Lake NY US Fogel, Keith E. Clinton Corners NY US Murphy, Richard J. Pleasantville NY US Sadana, Devendra K. US

US-CL-CURRENT: 438/478

Full Title Citation Front Review Classification Date Reference Sequences Attachments Claims KMC Draw De

4. Document ID: US 20040242006 A1

L7: Entry 4 of 4

File: PGPB

Dec 2, 2004

PGPUB-DOCUMENT-NUMBER: 20040242006

PGPUB-FILING-TYPE: new

DOCUMENT-IDENTIFIER: US 20040242006 A1

TITLE: SiGe lattice engineering using a combination of oxidation, thinning and

epitaxial regrowth

PUBLICATION-DATE: December 2, 2004

INVENTOR-INFORMATION:

NAME CITY STATE COUNTRY RULE-47 Bedell, Stephen W. Wappingers Falls NY US Chen, Huajie Wappingers Falls NY US Fogel, Keith E. Mohegan lake NY US Sadana, Devendra K. Pleasantville NY US

US-CL-CURRENT: <u>438/692</u>

| Full | Title Citation | Front | Review | Classification | Date | Reference | Sequences | Attachments | Claims | KMC | Drawa De | |
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